IN THE CLAIMS:

Please amend the claims as shown below.

Claims 1 and 2 (canceled)

Claim 3 (previously presented): A substrate cleaning tool as claimed in Claim 21, wherein the substrate cleaning tool is capable of rotating against the substrate.

Claim 4 (canceled)

Claim 5 (previously presented): A substrate cleaning tool as claimed in Claim 21, wherein each of said members has a number of channels extending from the hollow channel.

Claim 6 (canceled)

Claim 7 (previously presented): A substrate cleaning tool as claimed in Claim 21, wherein the members comprise a hydrophilic material.

Claims 8-13 (canceled)

Claim 14 (previously presented): A substrate cleaning apparatus as claimed in Claim 23, wherein the scrub arm is provided with a driving mechanism for driving the substrate cleaning tool.

Claim 15 (original): A substrate cleaning apparatus as claimed in Claim 14, wherein the driving mechanism moves the substrate cleaning tool up and down.

Claim 16 (original): A substrate cleaning apparatus as claimed in Claim 14, wherein the driving mechanism rotates the substrate cleaning tool.

Claim 17 (previously presented): A substrate cleaning apparatus as claimed in Claim 14, wherein the driving mechanism moves the substrate cleaning tool up and down and also rotates the substrate cleaning tool, the driving mechanism being provided with an elevator shaft being moved up and down and rotated, the elevator shaft being provided with a cleaning liquid passage therethrough for supplying the cleaning liquid to the substrate cleaning tool and being provided with a body at a lower end thereof, the members extending straight and having their respective one ends tied up in a bundle and mounted on the body.

Claim 18 (previously presented): A substrate cleaning apparatus as claimed in Claim 23, wherein the holder holds the substrate rotatably.

Claim 19 (previously presented): A substrate cleaning apparatus as claimed in Claim 23, further comprising a nozzle for ejecting cleaning liquid for rinsing.

Claim 20 (canceled)

Claim 21 (currently amended): A substrate cleaning tool for cleaning a substrate, comprising: a plurality of flexible thready members, wherein

each of the members has a hollow channel and is comprised of comprises a water permeable material,

the members extend straight and have their respective one ends tied up in a bundle,
the members are attached to a body by turns, the body having a cleaning liquid passage
for supplying the cleaning liquid to the members, and

members of a first group of the members are longer than members of a second group of the members;

members of the second group are disposed between members of the first group; and the substrate is a semiconductor wafer or a LCD substrate glass.

Claim 22 (currently amended): A substrate cleaning tool for cleaning a substrate, comprising: a plurality of flexible thready members, wherein

each of the members has a hollow channel and is comprised of comprises a water repellant material,

the members extend straight and have their respective one ends tied up in a bundle,
the members are attached to a body by turns, the body having a cleaning liquid passage
for supplying the cleaning liquid to the members, and

members of a first group of the members are longer than members of a second group of the members

members of the second group are disposed between members of the first group; and the substrate is a semiconductor wafer or a LCD substrate glass.

Claim 23 (currently amended): A substrate cleaning apparatus for cleaning a substrate, comprising:

a plurality of flexible thready members;

a scrub arm for holding the substrate cleaning tool; and

a holder for holding a substrate to be cleaned by the substrate cleaning tool,

wherein each of the members has a hollow channel and is comprised of comprises a water permeable material,

the members extend straight and have their respective one ends tied up in a bundle and attached to a body by turns, the body having a cleaning liquid passage for supplying the cleaning liquid to the members, and

members of a first group of the members are longer than members of a second group of the members

members of the second group are disposed between members of the first group; and

the substrate is a semiconductor wafer or a LCD substrate glass.

Claim 24 (currently amended): A substrate cleaning tool for cleaning a substrate, comprising:

- a plurality of flexible thready members;
- a scrub arm for holding the substrate cleaning tool; and
- a holder for holding a substrate to be cleaned by the substrate cleaning tool,

wherein each of the members has a hollow channel and is comprised of comprises a water repellant material,

the members extend straight and have their respective one ends tied up in a bundle and attached to a body by turns, the body having a cleaning liquid passage for supplying the cleaning liquid to the members, and

members of a first group of the members are longer than members of a second group of the members

members of the second group are disposed between members of the first group; and the substrate is a semiconductor wafer or a LCD substrate glass